

Epitaxial Growth of Cesium Potassium Antimonide Photocathode

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Outline

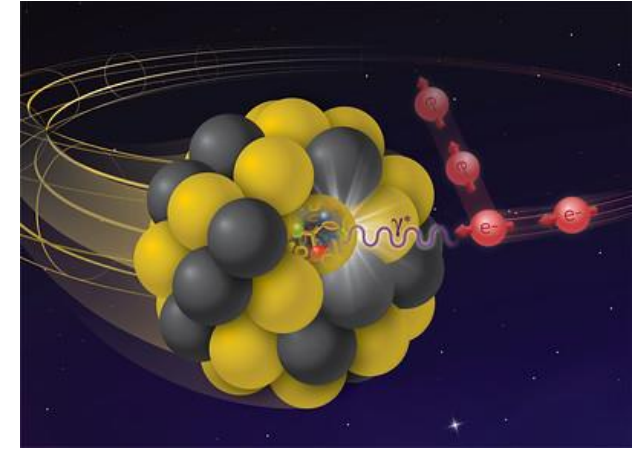
- ❑ Introduction: Photocathode and epitaxial growth
- ❑ Experimental Details
- ❑ PLD: epitaxial growth
 - ❑ RHEED, XRD, XRR, GISAXS, XRF results
 - ❑ Spectral response
- ❑ Thermal: Epitaxial growth
 - ❑ RHEED results
 - ❑ Spectral response
- ❑ Conclusions
- ❑ Acknowledgement

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- **Introduction: Photocathode and epitaxial growth**
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Unpolarized photocathodes for EIC electron cooling

- ❑ To maintain a luminosity of $L= 10^{34}cm^{-2}s^{-1}$ in the Electron Ion Collider (EIC) during long collision runs, it is desirable to cool the hadron beams in order to balance emittance growth rates due to intrabeam scattering (IBS)
- ❑ Electron cooling is a promising technique to improve the luminosity of high current beams and has been demonstrated to cool proton beams



Photocathode

- ❑ Cathode is origin of the generated electrons, which could be a metal, a semiconductor.
- ❑ Photocathode: Convert photon to electron (photoelectric effect), electron emits in vacuum.
- ❑ Photoemission offers advantages, for example that electron bunches can be time structured.

Electron beam required for e-cooling in EIC

High average current (> 100 mA)

High bunch charge (1 nC)

Long lifetime (> 1 week)

Low emittance

- ❑ Fast development of the particle accelerator devices and the strong desire to achieve higher bunch charges and currents leads to the usage of semiconductor photocathodes such as alkali antimonide (K_2CsSb), Cesium antimonide ($Cs-Sb$), cesium telluride (Cs_2Te) or gallium arsenide ($GaAs$).

Epitaxial growth of Photocathode

- ❑ Epitaxy: The name epitaxy has Greek roots: “epi” means “on” and “taxis” means “in ordered manner”. Epitaxy refers to the growth of a single crystalline film on a single crystalline substrate.
- ❑ Epitaxial Growth of Photocathode: Large or single crystal photocathode generate low mean transverse energy due to smooth surface and low grain boundary scattering rate.
- ❑ Epitaxial growth with lattice matching substrate is essential to make large/single crystal photocathode.

Our goal

- ❑ Our main goal is to grow epitaxial semiconductor photocathode thin film.
- ❑ And achieve high quantum efficiency with epitaxial photocathode.

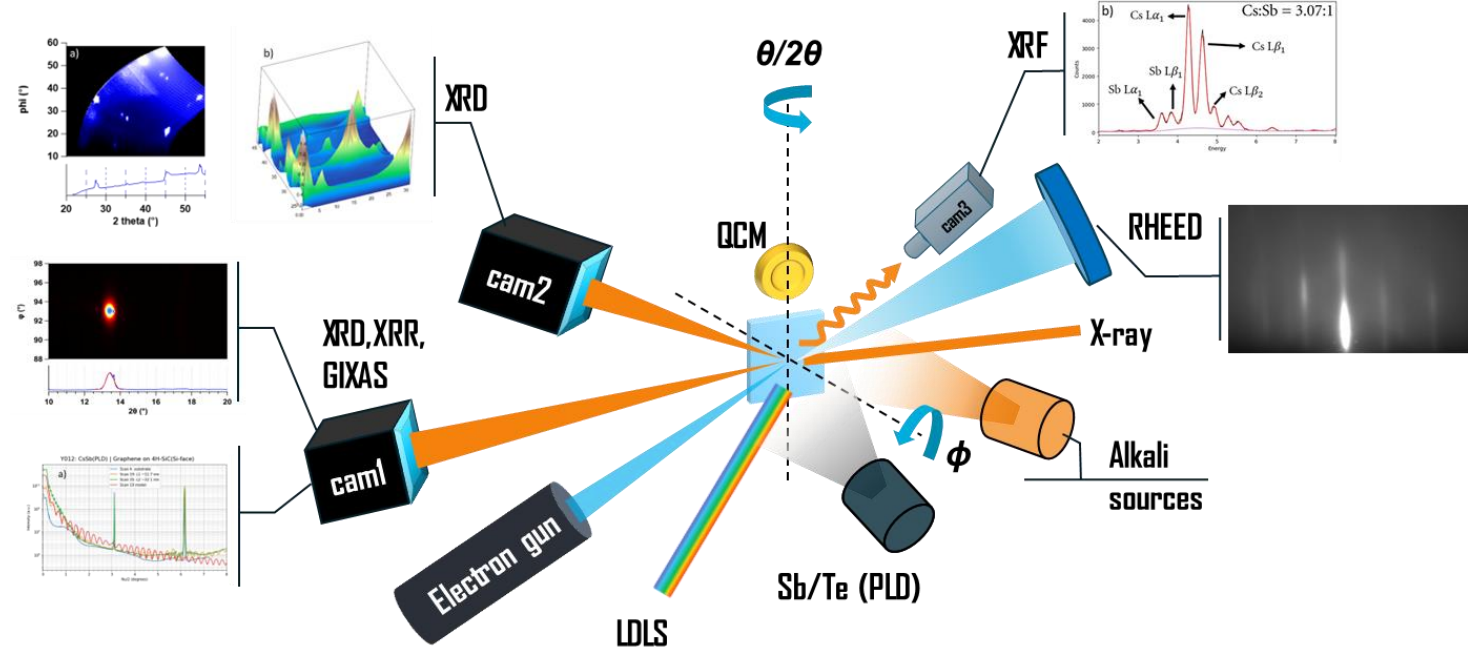
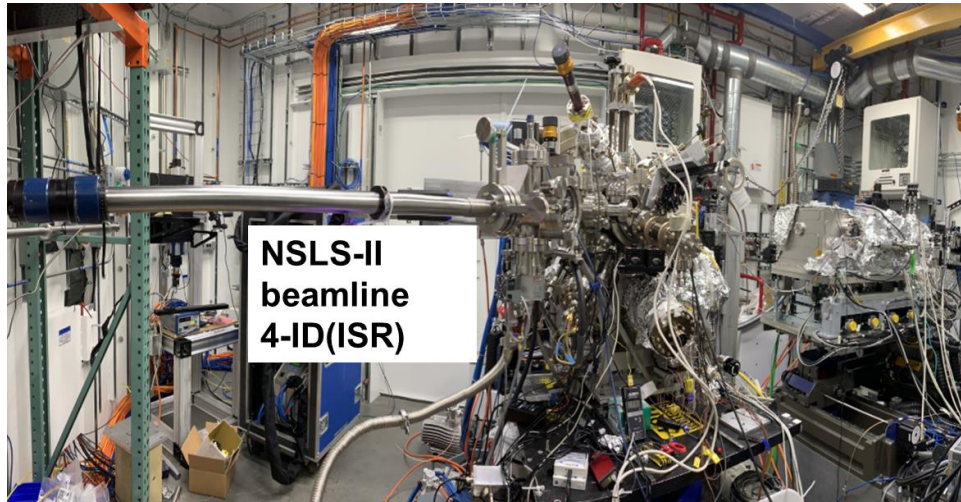
Introduction

- ❑ Epitaxial growth of Cesium Potassium Antimonide (K_2CsSb), deposited on different substrates: New substrate, 4H-SiC.
- ❑ Epitaxial growth: Compare PLD and thermal-assisted growths.

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The BNL UHV photocathode growth system at beamline 4-ID, Integrated In situ and Resonant Hard X-ray Studies (ISR), NSLS-II for in situ and real time x-ray characterization. schematic of X-ray techniques (XRR, XRD, GISAXS, XRF) used to characterize the photocathode properties.



Evaporators:

- Thermal Sb/Te
- Alkali metals
- PLD Sb/Te

Characterization:

- Reflection high energy electron diffraction (RHEED): epitaxial growth and crystalline structural details.
- X-ray diffraction (XRD): crystalline structure.
- X-ray reflectivity (XRR): thin film thickness, roughness, electron density.
- Grazing incidence small angle x-ray scattering (GISAXS): Structural details both from surface and interface.
- X-ray fluorescence (XRF): Stoichiometry of Photocathode
- Quantum efficiency (QE) measurement: QE of photocathodic thin film.
- Quartz crystal microbalance (QCM): thin film thickness

- K and Cs deposited using effusion cell.
- Sb deposited with both PLD and thermal growth.

Epitaxial Growth of K_2CsSb

PLD and thermal evaporation assisted epitaxial growth
at 4ID, NSLS-II, BNL

Sample 1

K_2CsSb

New Substrate

- Sb deposited using PLD.

Sample 2

K_2CsSb

New Substrate

- Substrate is heat clean from Sample-1.
- Sb deposited using Thermal evaporation.

Sample 3

K_2CsSb

4H-SiC

- Sb deposited using Thermal evaporation.

For all samples

- Cs and K were deposited using effusion cells.
- Layer 1: K_2CsSb on substrate, for structural study
- Layer 2: Growth of another layer of K_2CsSb on Layer 1
- Layer 3: Growth of photocathode high enough thickness to achieve high QE.

K_2CsSb (Layer 3)

K_2CsSb (Layer 2)

K_2CsSb (Layer 1)

Substrate

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K_2CsSb (Layer 3)

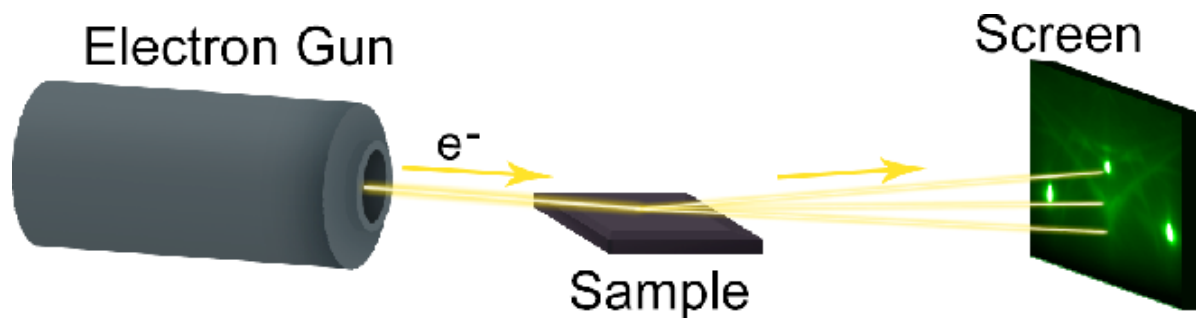
K_2CsSb (Layer 2)

K_2CsSb (Layer 1)

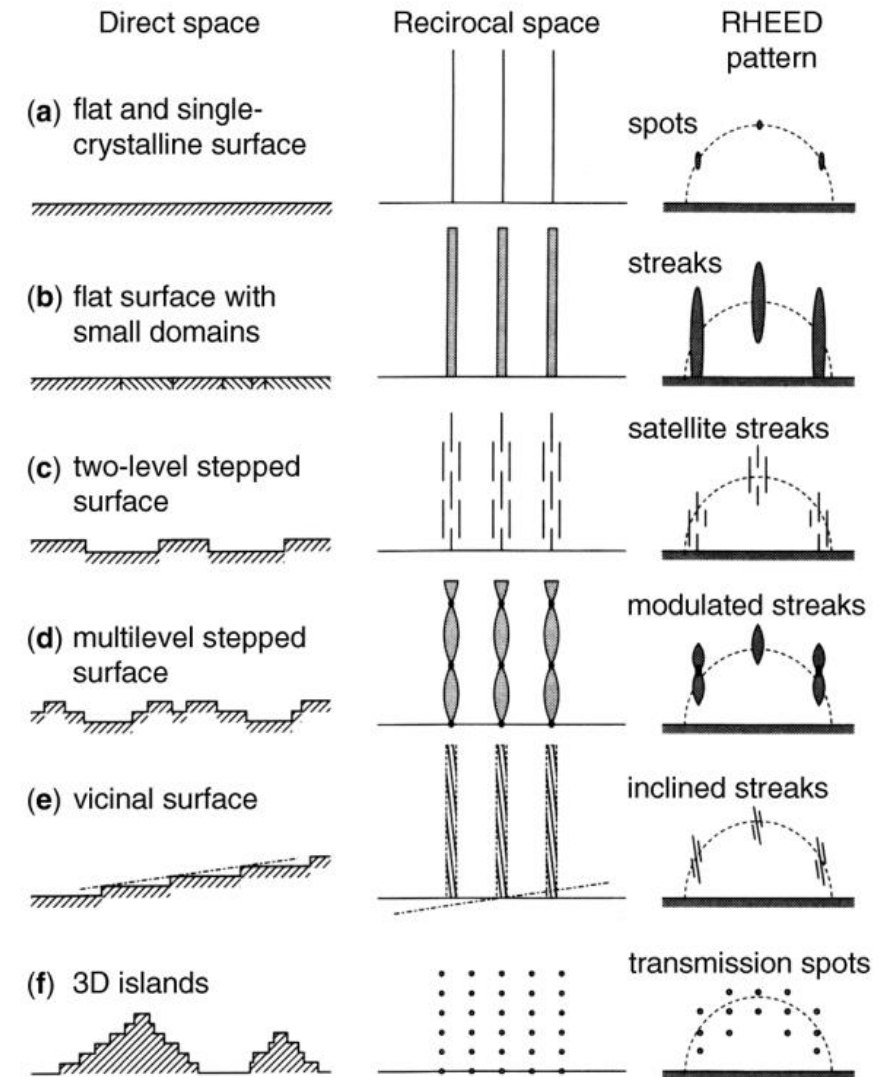
Substrate

RHEED of Photocathode

- ❑ RHEED provides -surface symmetry, real space lattice spacing, crystalline degree of perfection
- ❑ Photocathodic thin film, K_2CsSb grown on 4H-SiC, new substrate.
- ❑ RHEED has been performed after the completion of each growth.
- ❑ Our goal is to
 - Study crystalline structure of photocathodic thin film after each growth
 - Also, study of angular dependence of crystalline structure with in-plane rotation
 - Find out lattice mismatch, strain of thin films

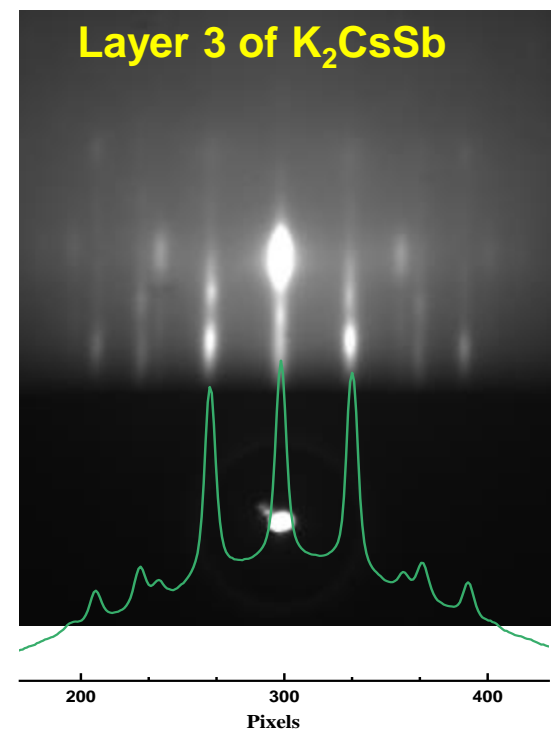
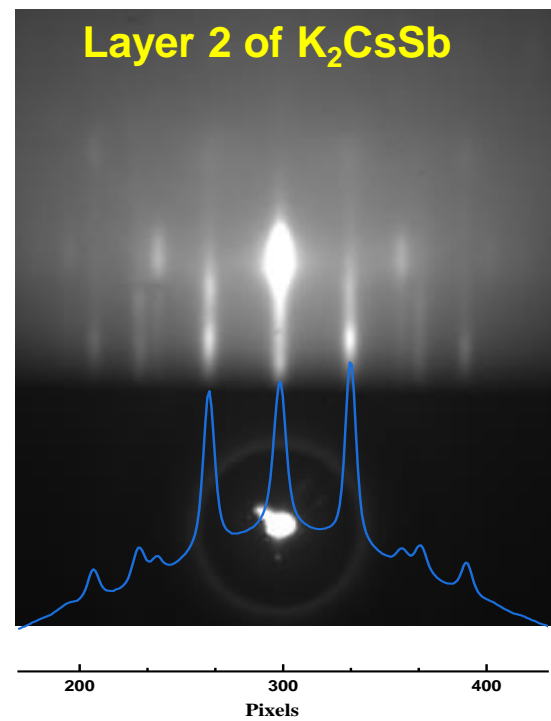
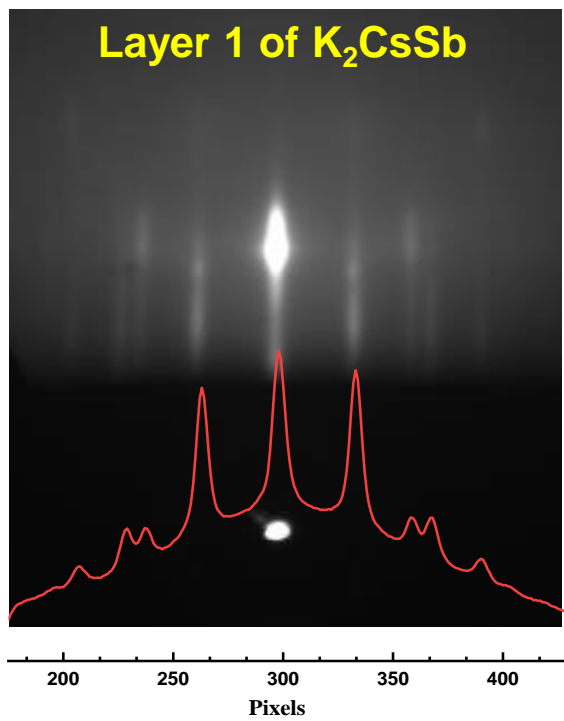
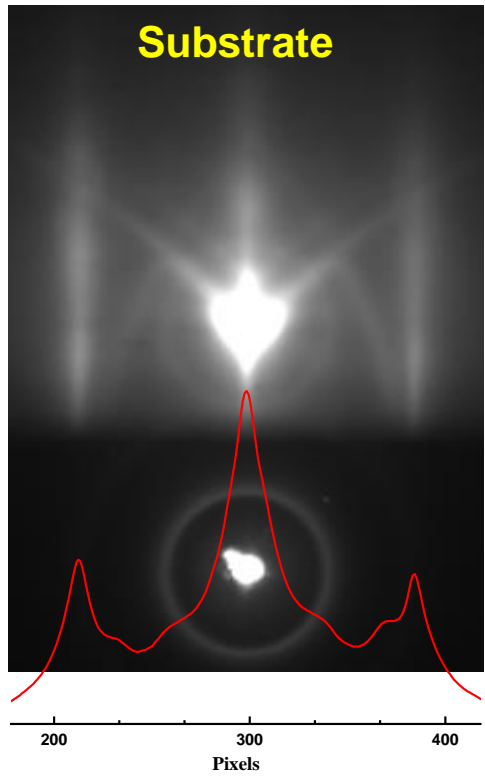


Schematic of RHEED [Derriche et al. 2019]



Schematics of various kinds of realistic surfaces, in real-space morphology, in reciprocal space, and their RHEED patterns [Hasegawa, 2012]

RHEED of Sample 1: Sb deposited using PLD



XRF of K₂CsSb (Layer 3)
Cs/Sb: 1.29;
K/Sb: 1.88

K ₂ CsSb/New Substrate (Layer 1)			
Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	34.5	4.97	111
2 nd	60	2.86	122
3 rd	69	2.49	222
4 th	91.5	1.87	133

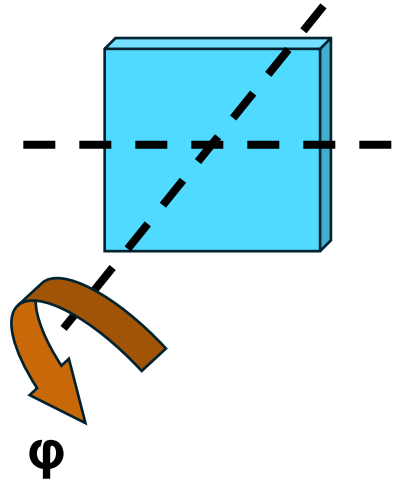
RHEED of K₂CsSb

- ❑ RHEED image shows epitaxial growth.
- ❑ Streaks represent smooth surfaces with small domains.
- ❑ With increasing thickness roughness increases.

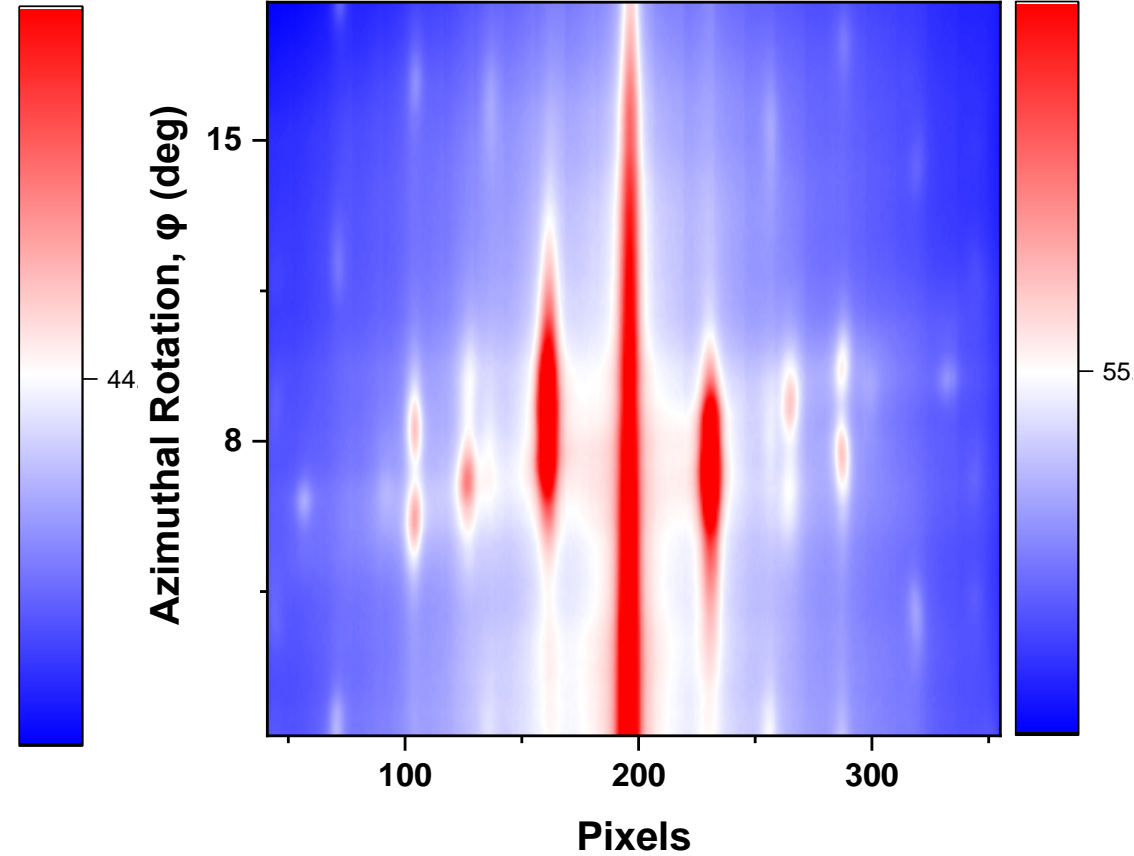
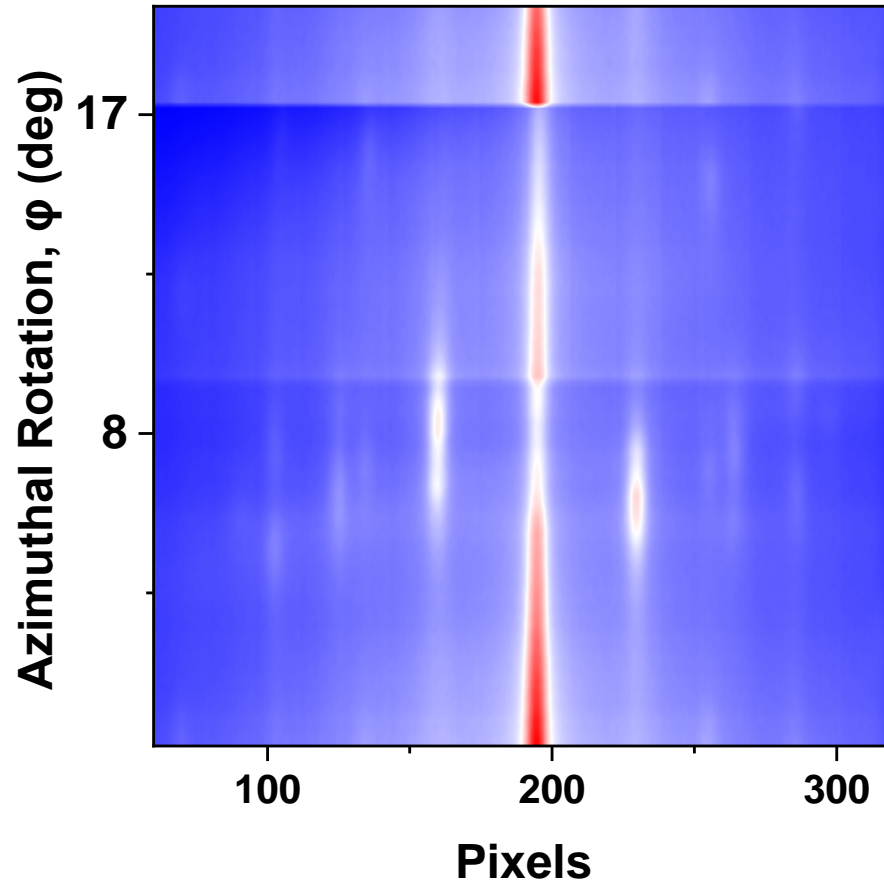
Azimuthal angular dependence of RHEED from Sample-1

Layer 1 of K_2CsSb

Layer 3 of K_2CsSb

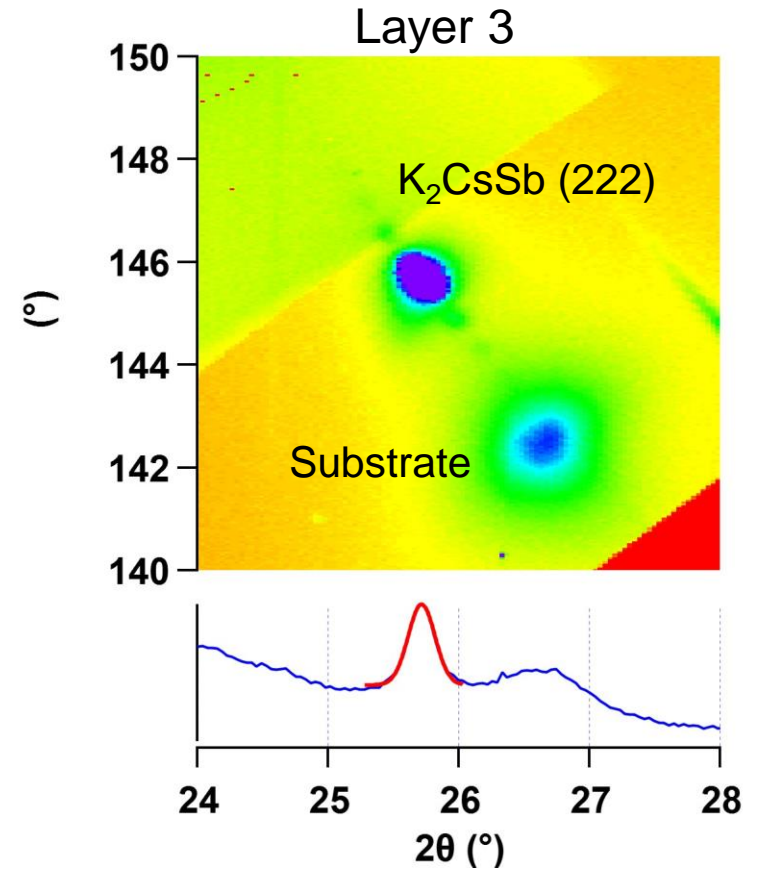
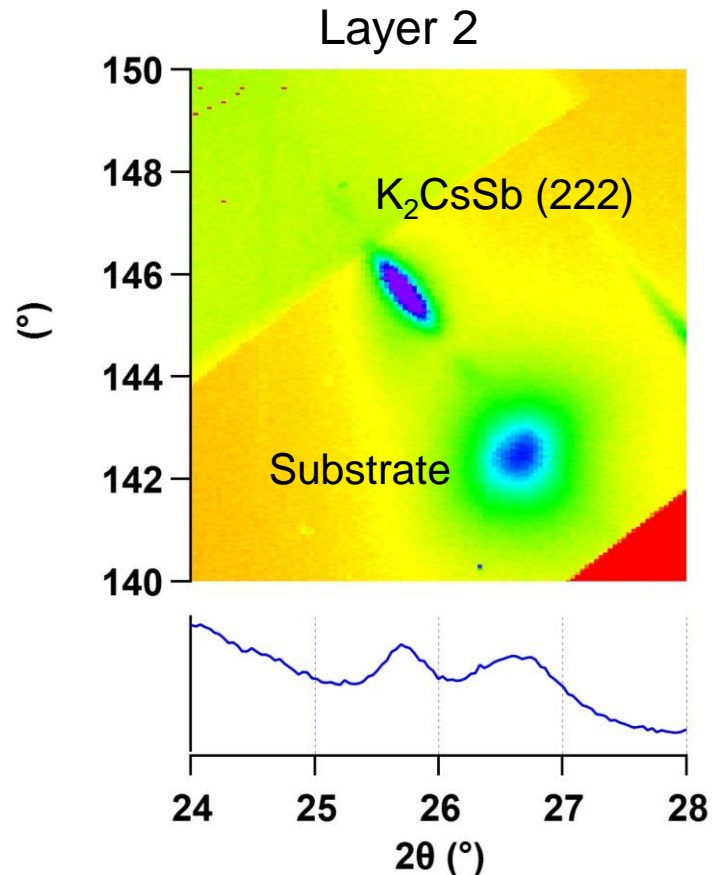
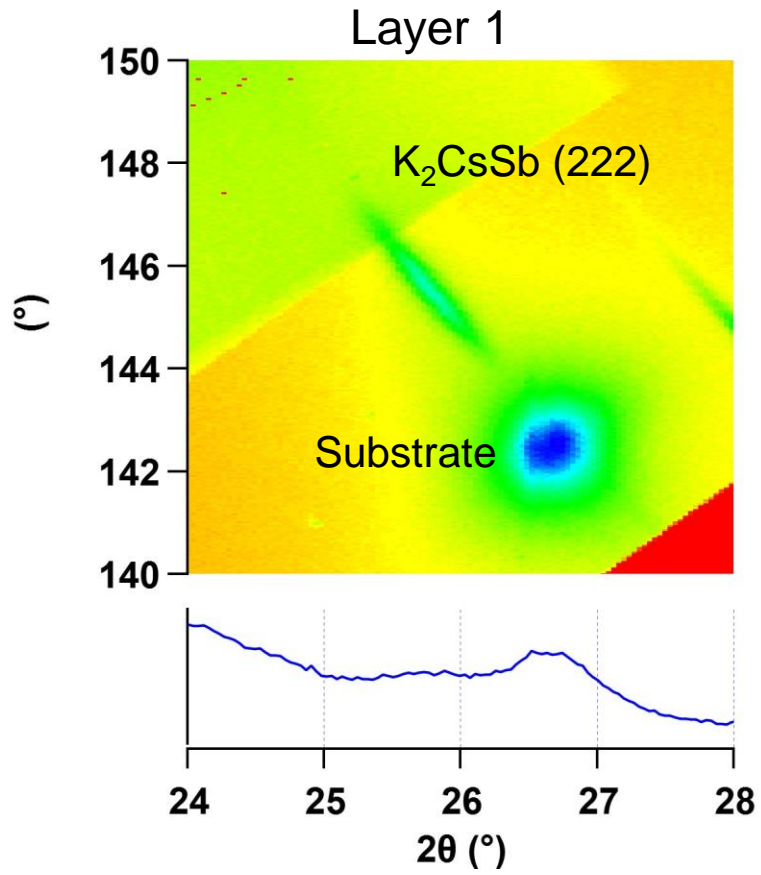


Schematic of azimuthal sample rotation



Azimuthal angular dependence observed

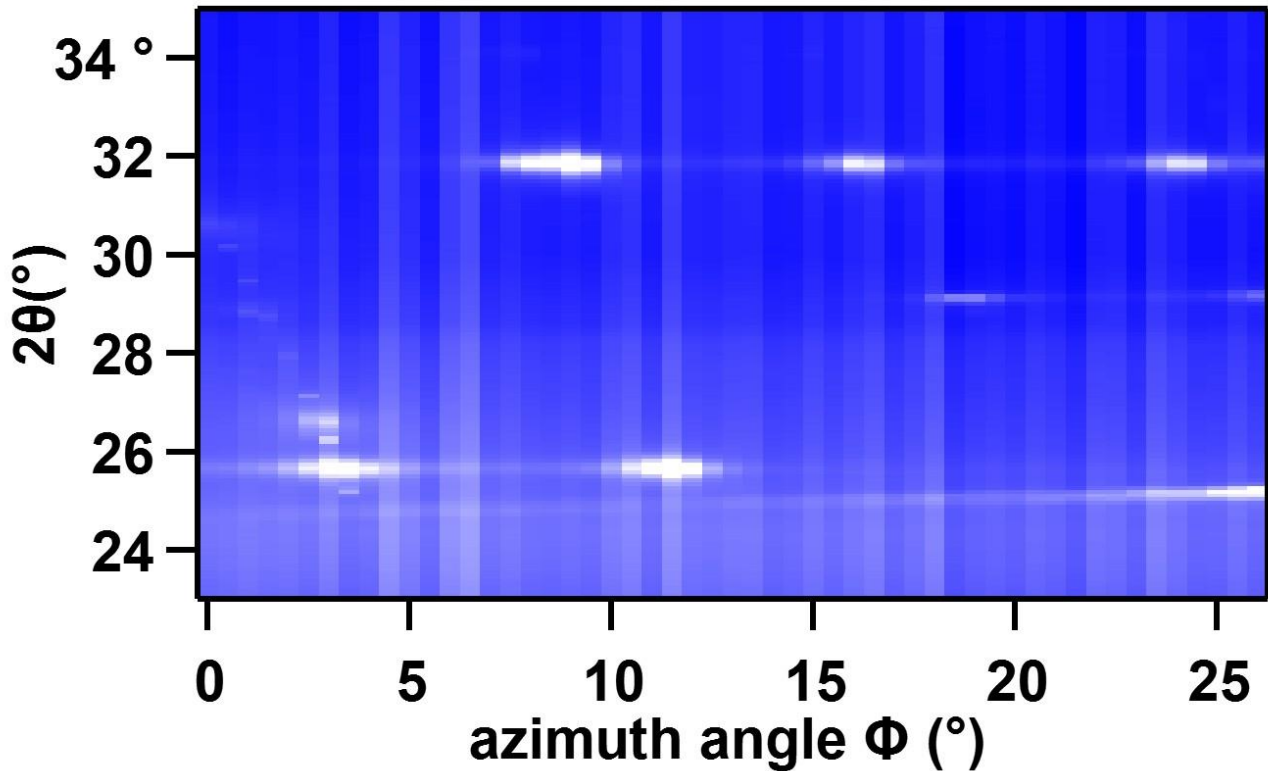
XRD of K_2CsSb /New Substrate (Sample-1): Sb deposited using PLD



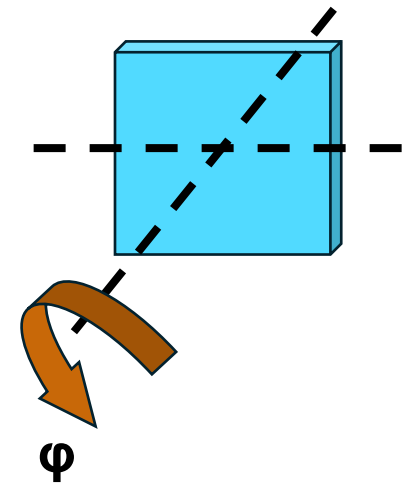
- ❑ Diffraction image at Bragg condition (222)
- ❑ Elongation structure is from Mosaicity and strain from sample.
- ❑ Grain size of Layer-3 is 411 nm, where film thickness is 20 nm.

$x_0 = 25.715 \pm 0.00224$
width = 0.14515 ± 0.00415
Grain size: 411.30 nm

Azimuthal angular dependence of XRD from Sample-1



(133)
(004)
(222)



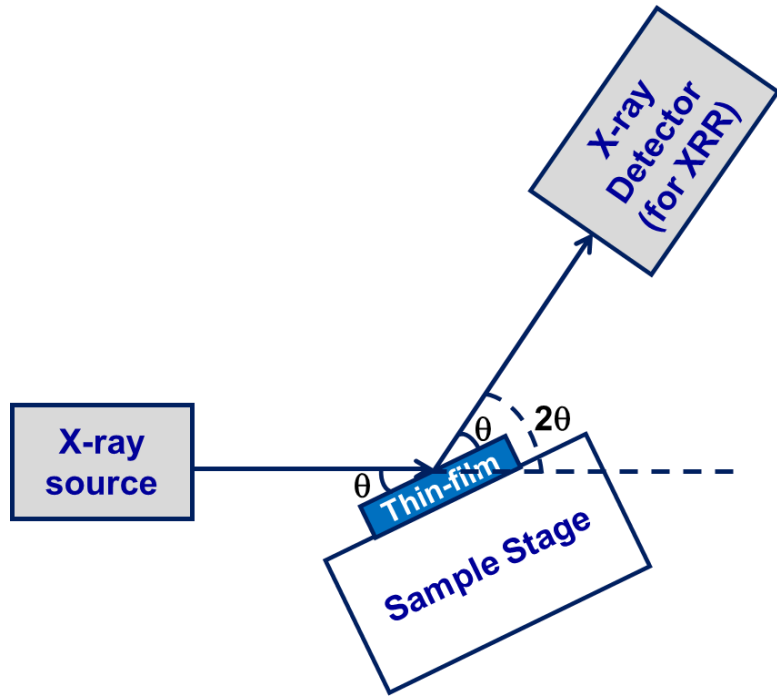
Schematic of azimuthal sample rotation

☐ Azimuthal angular dependence observed

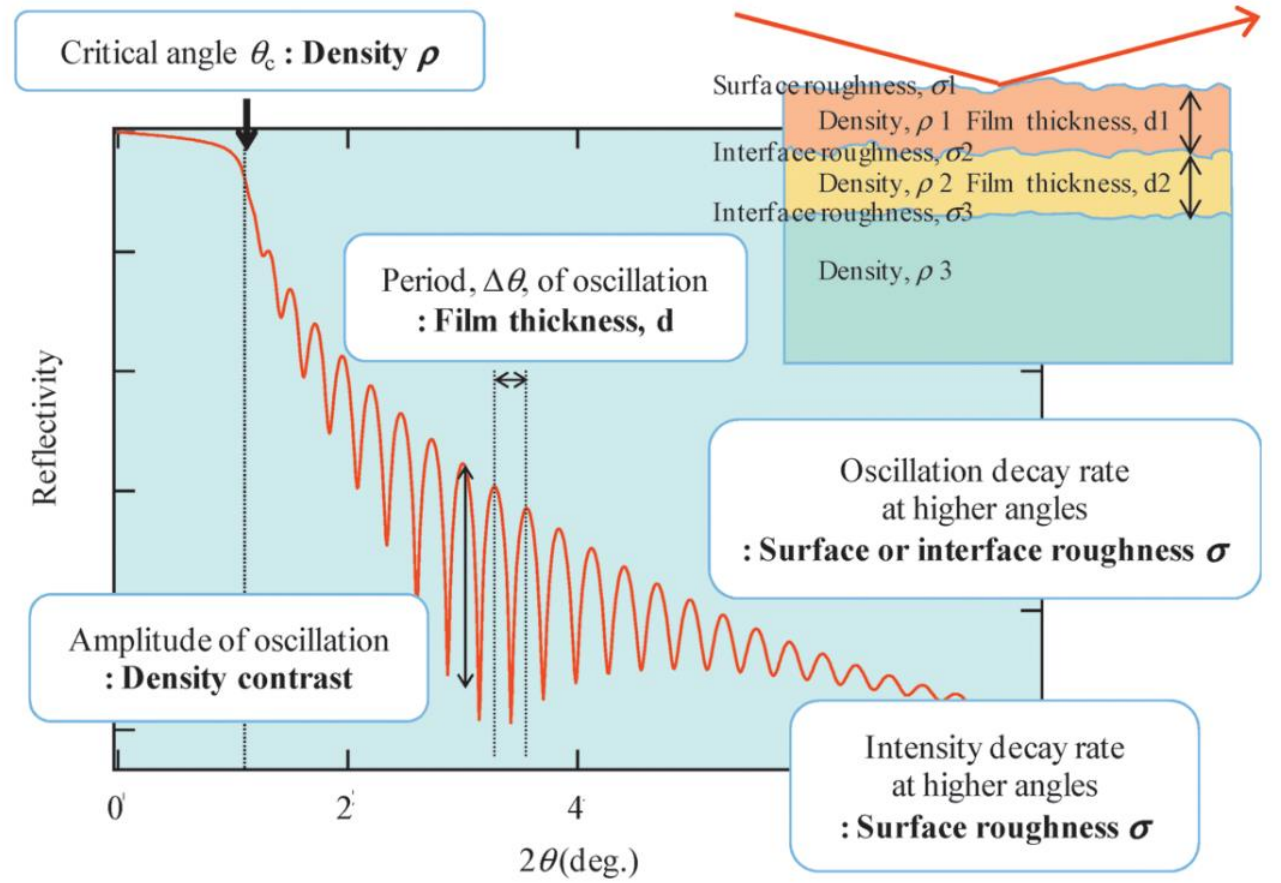
XRR of Photocathode

XRR provides thin-film's

- ❑ Film thickness $\propto 1/\Delta\theta$
- ❑ Electron density (ρ_e), $\theta_c \propto \sqrt{\rho_e}$
- ❑ Roughness, $R_{\text{flat}} * \exp(-4kz^2\sigma^2)$

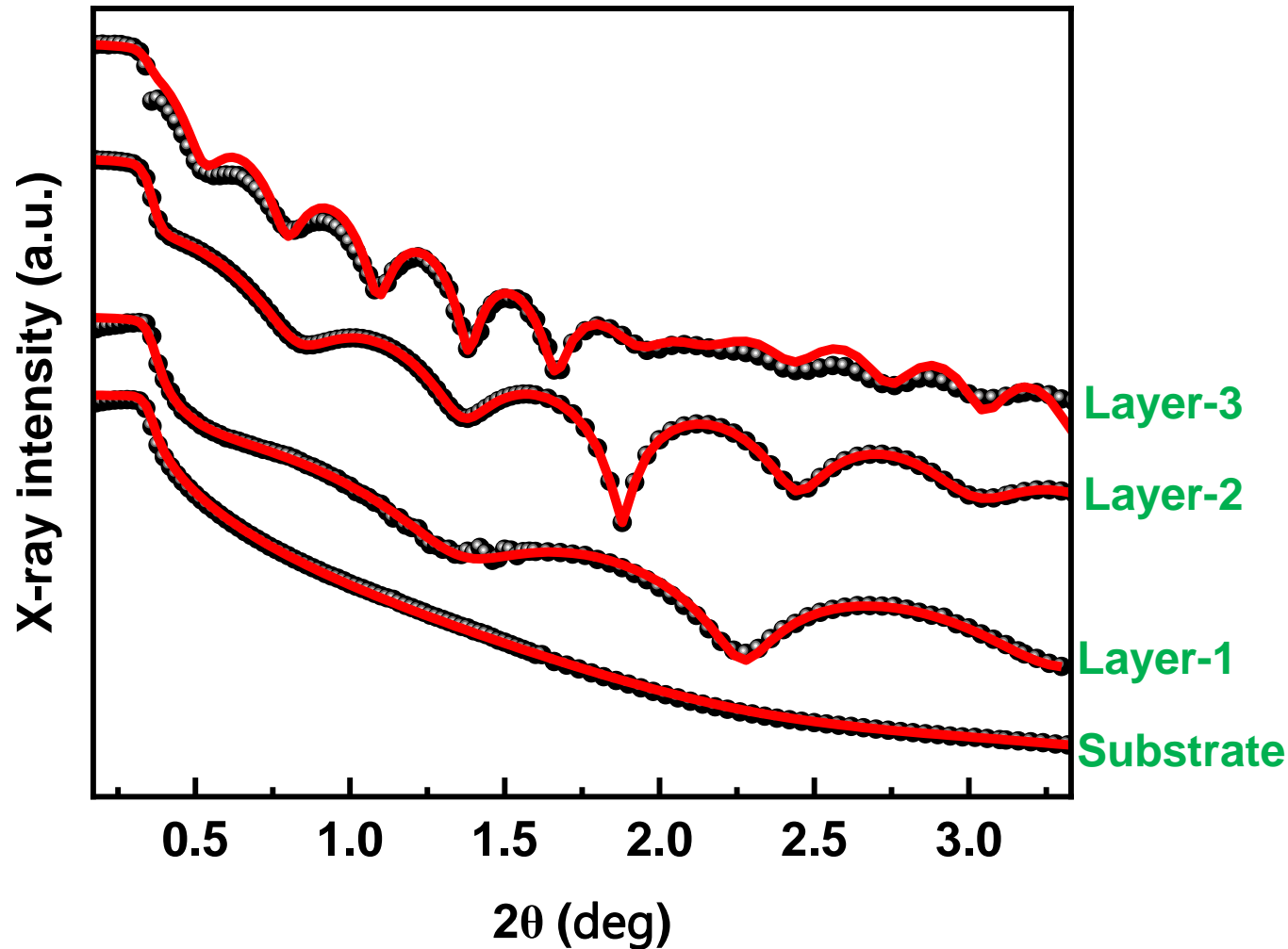


Schematic of XRR



Information provided by XRR [Yasaka, 2010]

XRR of K_2CsSb /New Substrate (Sample-1): Sb deposited using PLD



XRR	Thickness (nm)	Roughness (nm)
Substrate	NA	0.40
Layer 1	6	0.60
Layer 1+2	11	0.65
Layer 1+2+3	20	0.75

XRR of K_2CsSb

□ Roughness increased with increasing thickness of photocathode thin film.

Spectral response of K_2CsSb from Sample 1

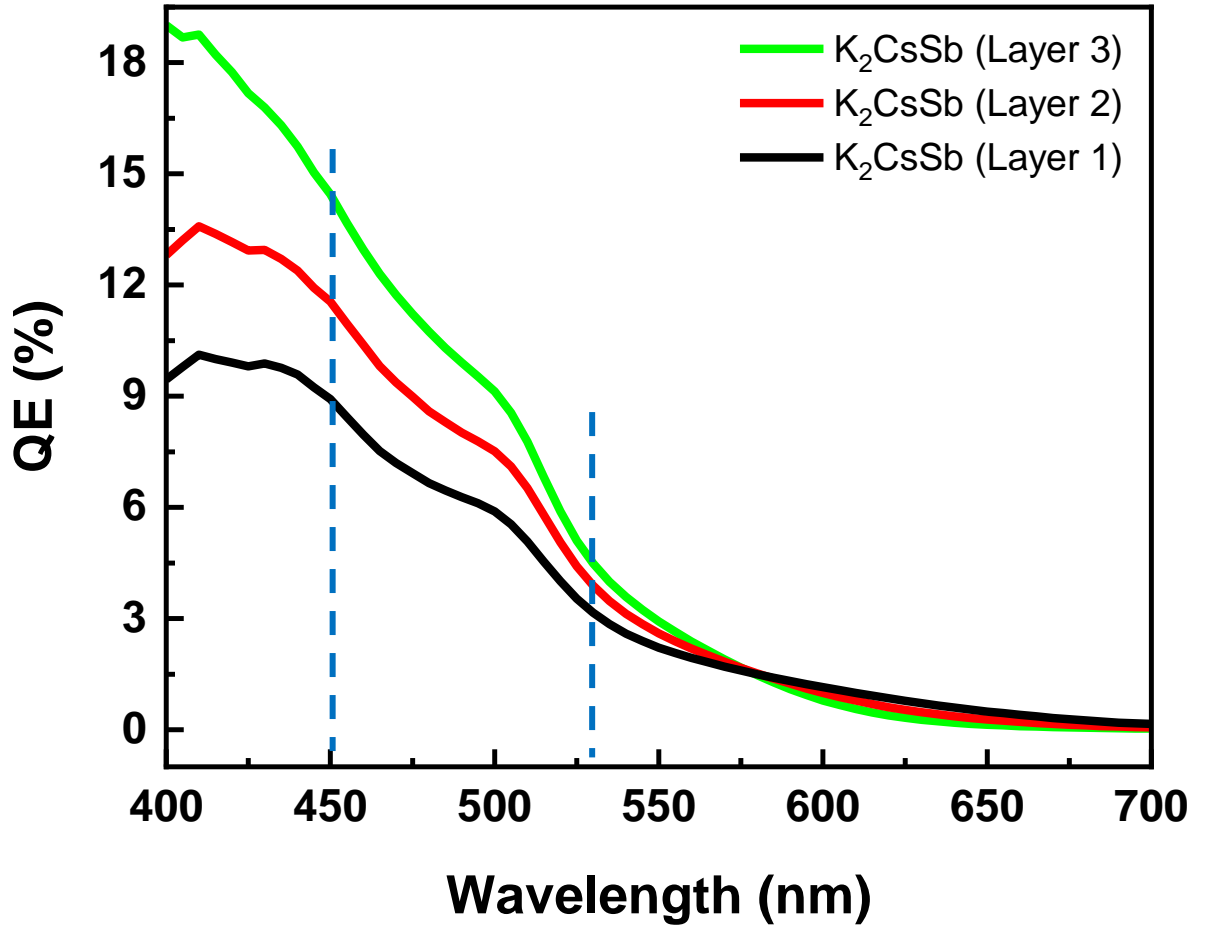
Quantum Efficiency (QE) of Photocathode

QE is one of the most important parameters, when dealing with photocathodes.

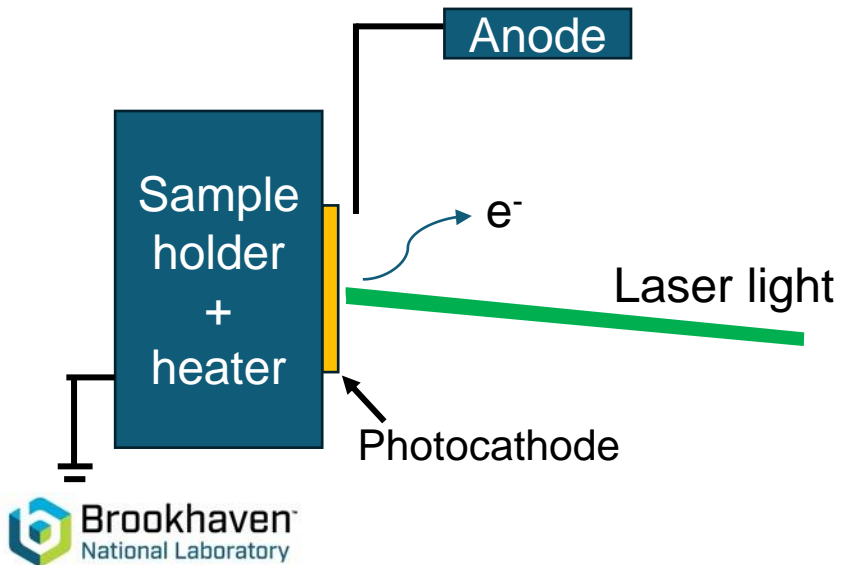
$$QE = \frac{N_{electrons}}{N_{photons}} = \frac{hc}{q_e} \times \frac{I}{\lambda P_{light}}$$

Where I is measured photocurrent from a photocathode, λ is incident wavelength and P_{light} is power of incident light.

Therefore, a maximum QE is achieved by a minimum laser



Wavelength (nm)	QE (%)		
	L1	L2	L3
450 (Blue)	8.9	11.6	14.5
530 (Green)	3.2	3.9	4.5



PLD assisted epitaxial growth (Sample-1)

- ❑ Successful in growing epitaxial thin film photocathode.
- ❑ RHEED provides
 - Epitaxial growth of photocathode
 - Photocathode film form is smooth
 - Azimuthal angular dependence observed
- ❑ XRR provides
 - Photocathode film thickness, roughness, electron density
 - Film roughness < 0.8 nm
- ❑ QE measurements provide QE of photocathode thin film
 - QE for green light 4.5 %.
- ❑ XRD provides crystalline structure not only from the surface but also from bulk.

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 - **Spectral response**
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Sample 1

K_2CsSb

New Substrate

- Sb deposited using PLD.

Sample 2

K_2CsSb

New Substrate

- Substrate is heat clean from Sample-1.
- Sb deposited using Thermal evaporation.

Sample 3

K_2CsSb

4H-SiC

- Sb deposited using Thermal evaporation.

For all samples

- Cs and K were deposited using effusion cells.
- Layer 1: K_2CsSb on substrate, for structural study
- Layer 2: Growth of another layer of K_2CsSb on Layer 1
- Layer 3: Growth of photocathode high enough thickness to achieve high QE.

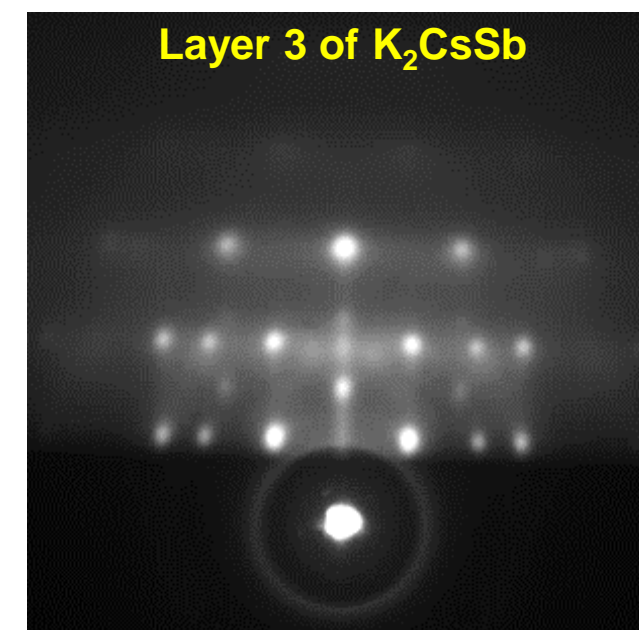
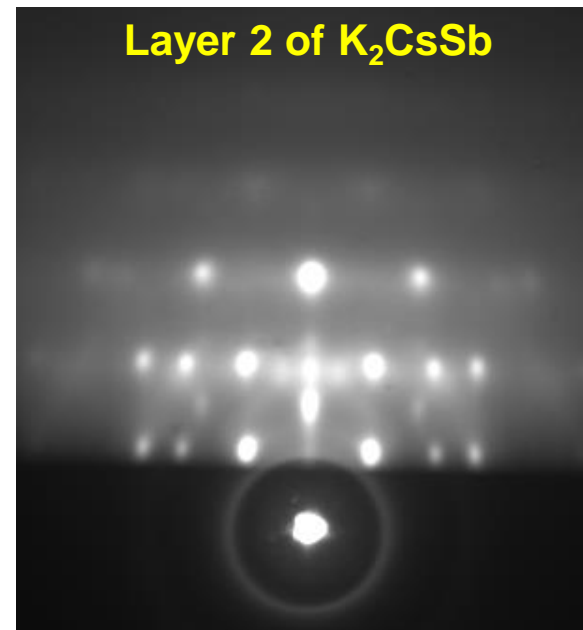
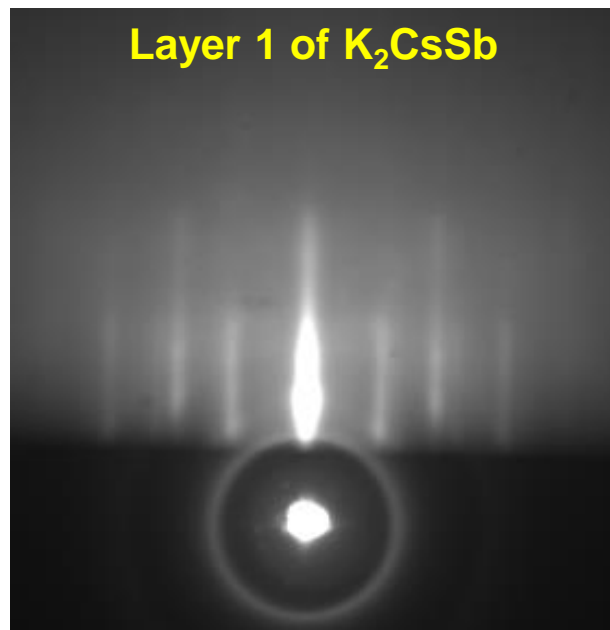
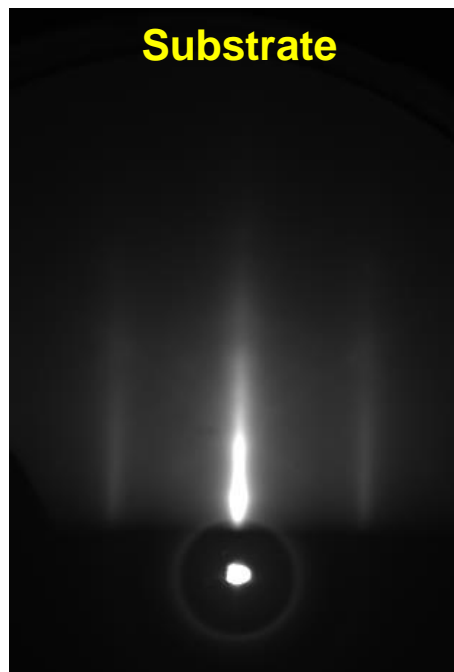
K_2CsSb (Layer 3)

K_2CsSb (Layer 2)

K_2CsSb (Layer 1)

Substrate

RHEED of K_2CsSb /New Substrate (Sample-2)



RHEED of K_2CsSb

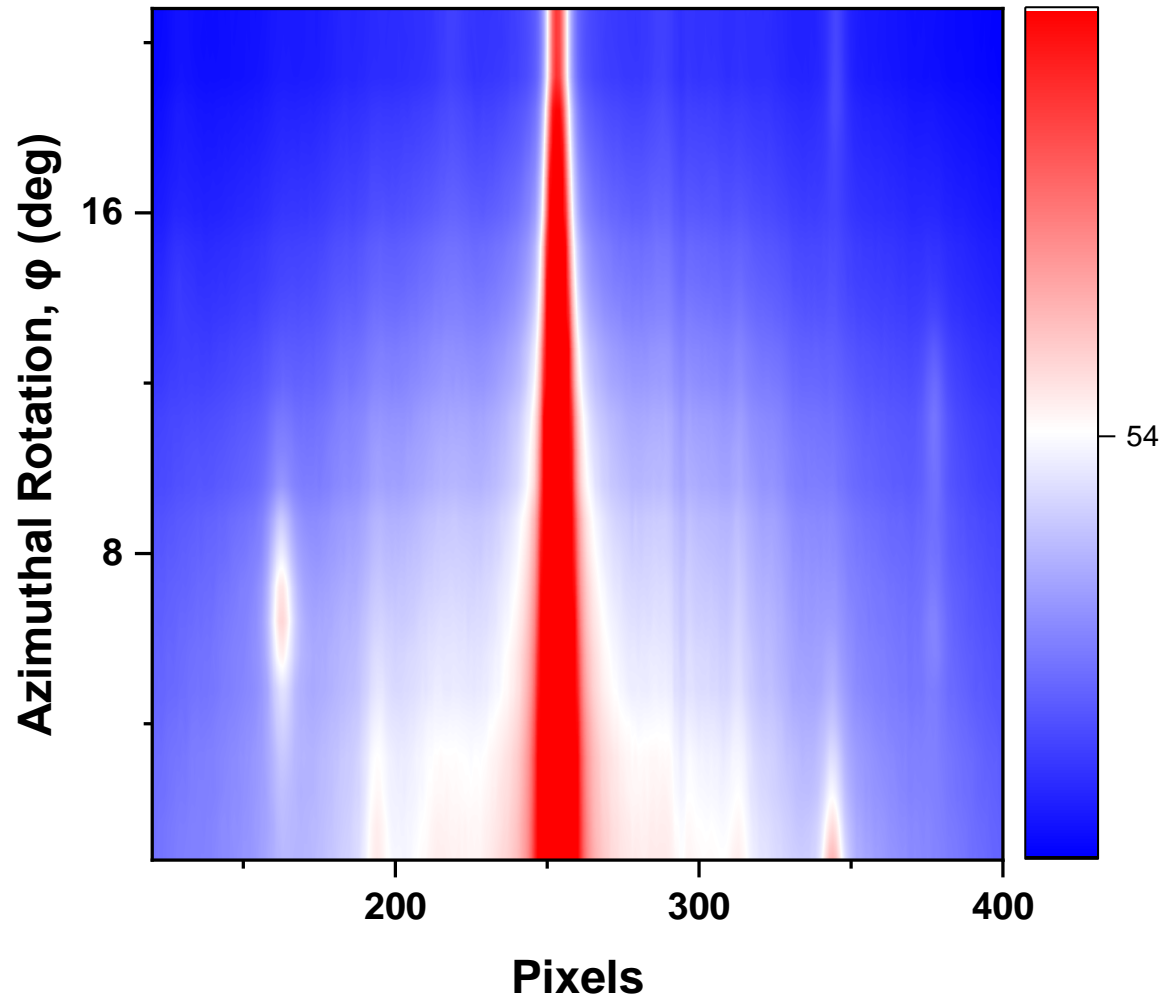
- RHEED image shows epitaxial growth.
- Streaks represent smooth surfaces with small domains.
- Dots represents 3D islands.

K_2CsSb on Substrate

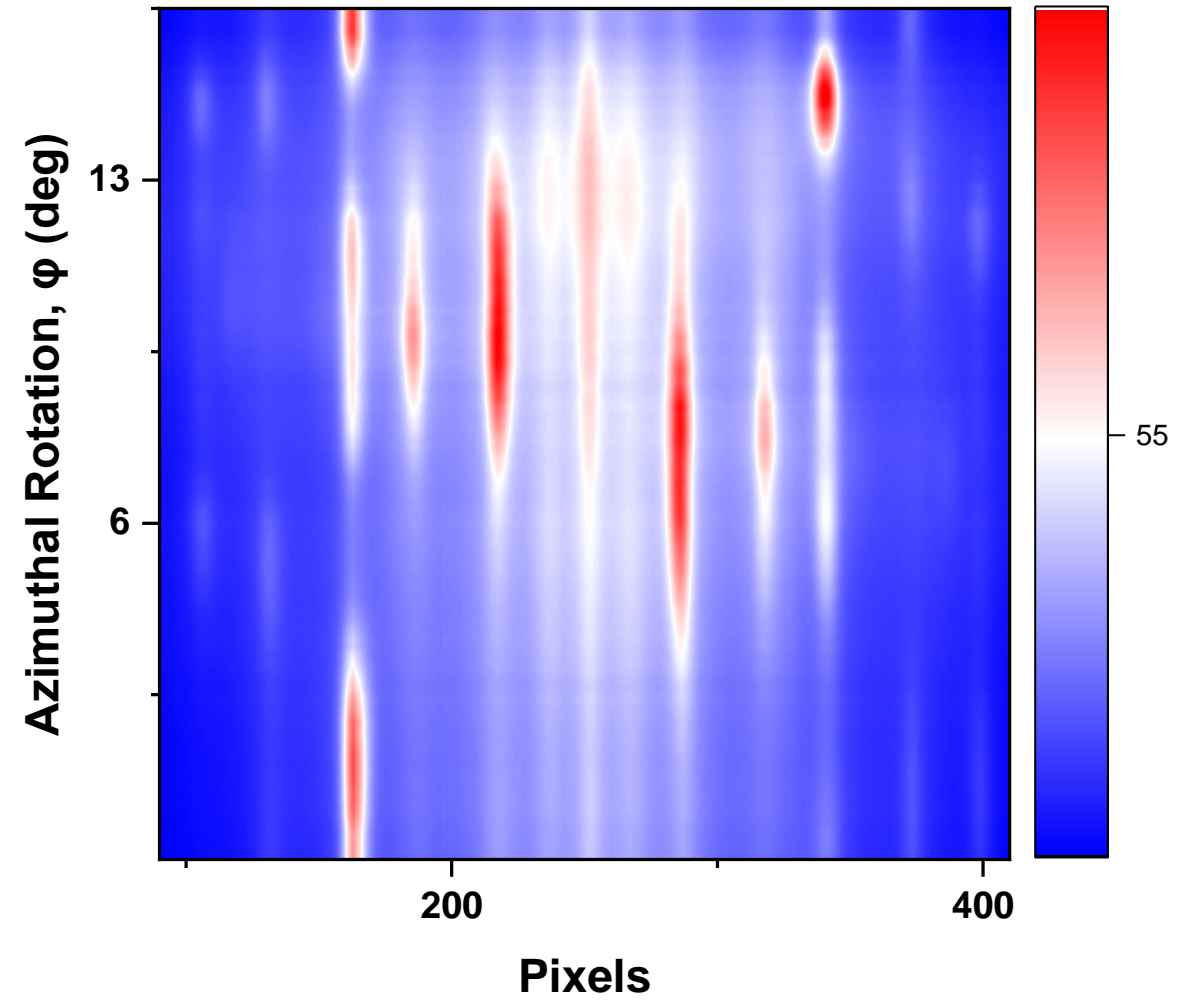
Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	34.55	4.96	111
2 nd	59	2.91	122
3 rd	69.25	2.48	222
4 th	90.4	1.90	133

Azimuthal angular dependence of RHEED from Sample-2

Layer 1 of K_2CsSb



Layer 3 of K_2CsSb



Sample 1

K_2CsSb

New Substrate

- Sb deposited using PLD.

Sample 2

K_2CsSb

New Substrate

- Substrate is heat clean from Sample-1.
- Sb deposited using Thermal evaporation.

Sample 3

K_2CsSb

4H-SiC

- Sb deposited using Thermal evaporation.

For all samples

- Cs and K were deposited using effusion cells.
- Layer 1: K_2CsSb on substrate, for structural study
- Layer 2: Growth of another layer of K_2CsSb on Layer 1
- Layer 3: Growth of photocathode high enough thickness to achieve high QE.

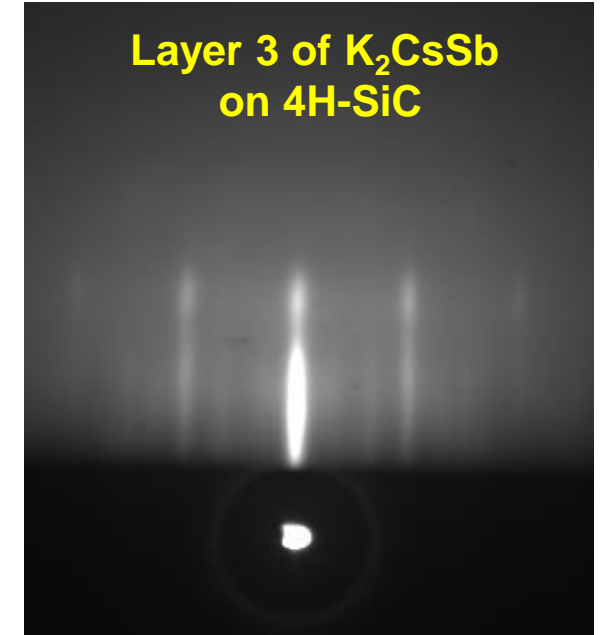
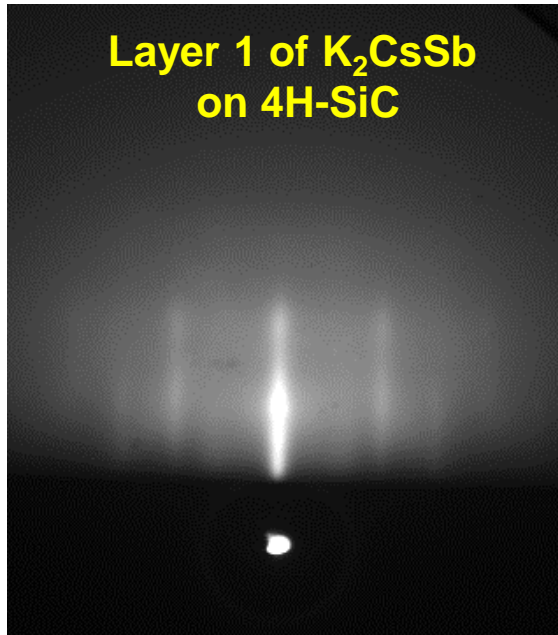
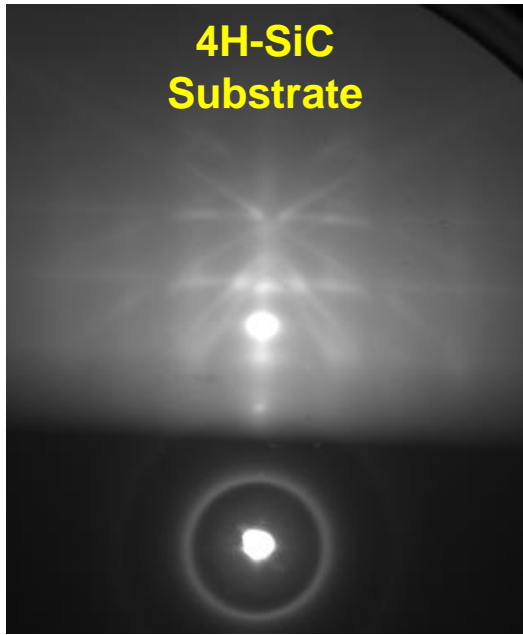
K_2CsSb (Layer 3)

K_2CsSb (Layer 2)

K_2CsSb (Layer 1)

Substrate

RHEED of $K_2CsSb/4H-SiC$ (Sample -3): Sb deposited using thermal evaporation



RHEED of $K_2CsSb/4H-SiC$

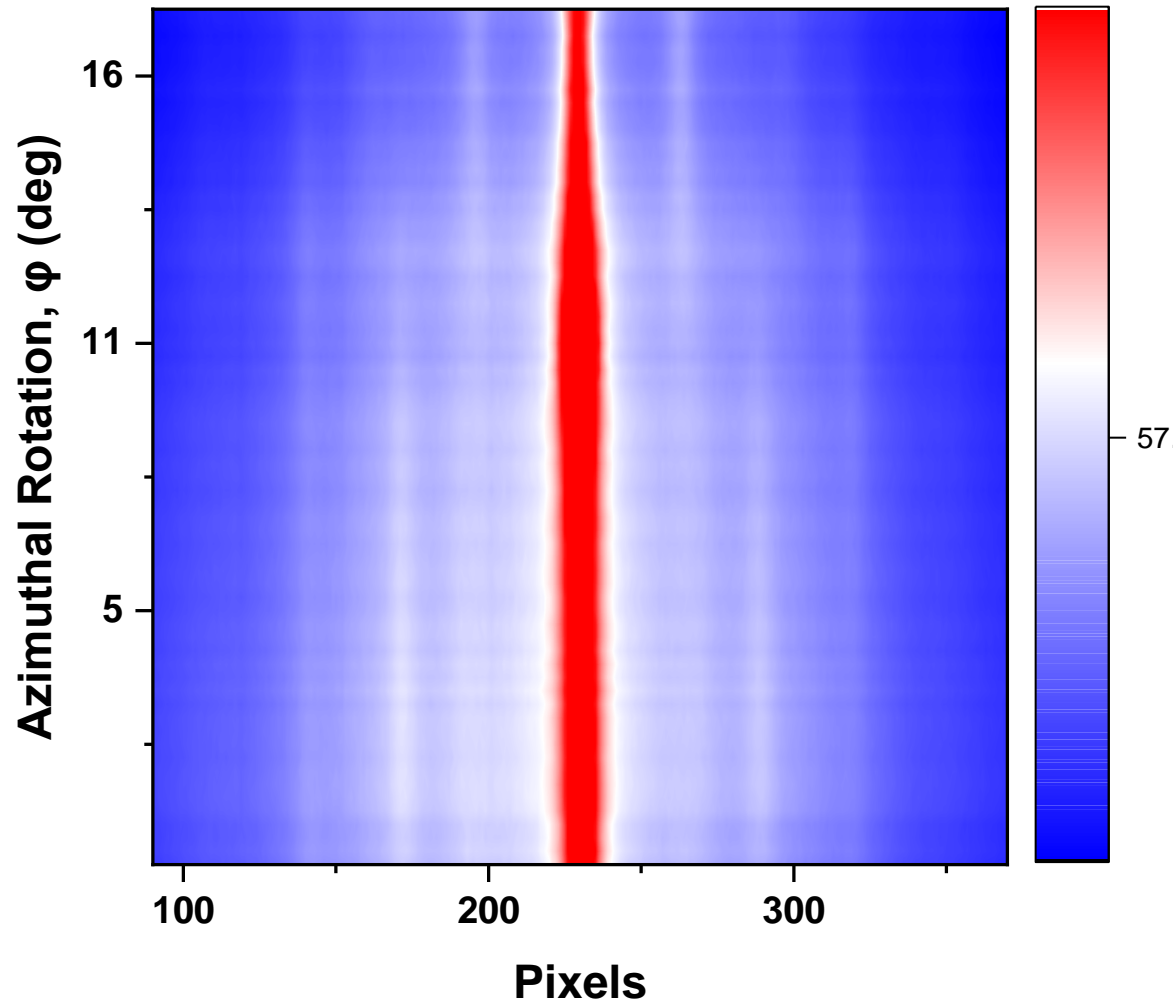
- ❑ RHEED image shows epitaxial growth.
- ❑ Streaks represent smooth surfaces with small domains.

K_2CsSb on 4H-SiC

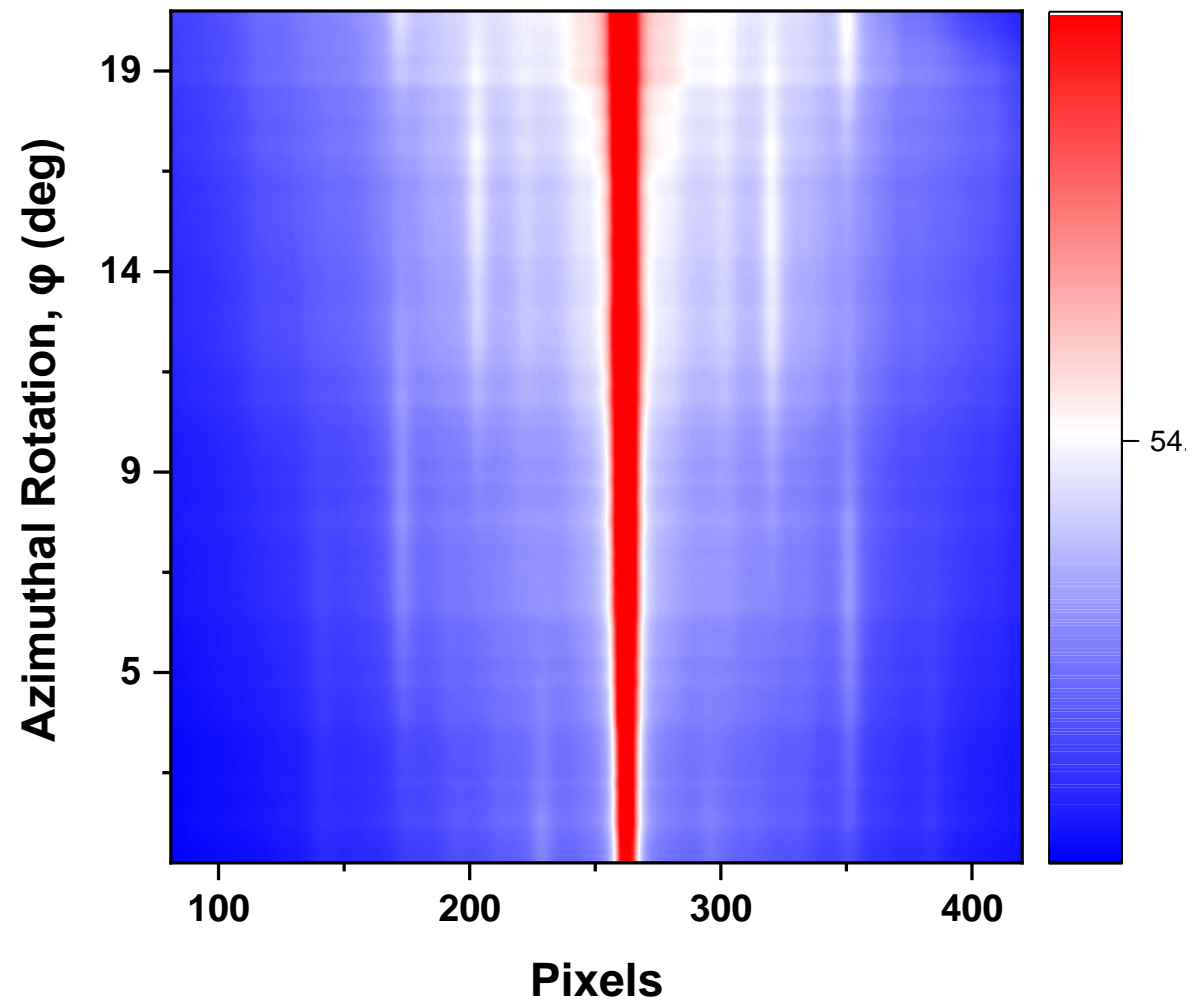
Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	38.9	4.41	002
2 nd	58.7	2.92	122
3 rd	74.75	2.29	004
4 th	89.15	1.92	133

Azimuthal angular dependence of RHEED from Sample-3

Layer 1 of K_2CsSb on 4H-SiC



Layer 3 of K_2CsSb on 4H-SiC



Compare of RHEED results of K_2CsSb

Conclusion from RHEED

- Similar structure and Sociometry found.
- Thermal evaporation produces rougher surface (need to confirm)

Sample-1: K_2CsSb on **New Substrate**, Sb deposited using **PLD**

Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	34.5	4.97	111
2 nd	60	2.86	122
3 rd	69	2.49	222
4 th	91.5	1.87	133

Sample-2: K_2CsSb on **New substrate**, Sb deposited using **Thermal**

Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	34.55	4.96	111
2 nd	59	2.91	122
3 rd	69.25	2.48	222
4 th	90.4	1.90	133

Sample-3: K_2CsSb on **4H-SiC**, Sb deposited using **Thermal evaporation**

Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	38.9	4.41	002
2 nd	58.7	2.92	122
3 rd	74.75	2.29	004
4 th	89.15	1.92	133

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K_2CsSb

New Substrate

- Sb deposited using PLD.

Sample 2

K_2CsSb

New Substrate

- Substrate is heat clean from Sample-1.
- Sb deposited using Thermal evaporation.

Sample 3

K_2CsSb

4H-SiC

- Sb deposited using Thermal evaporation.

For all samples

- Cs and K were deposited using effusion cells.
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- Layer 3: Growth of photocathode high enough thickness to achieve high QE.

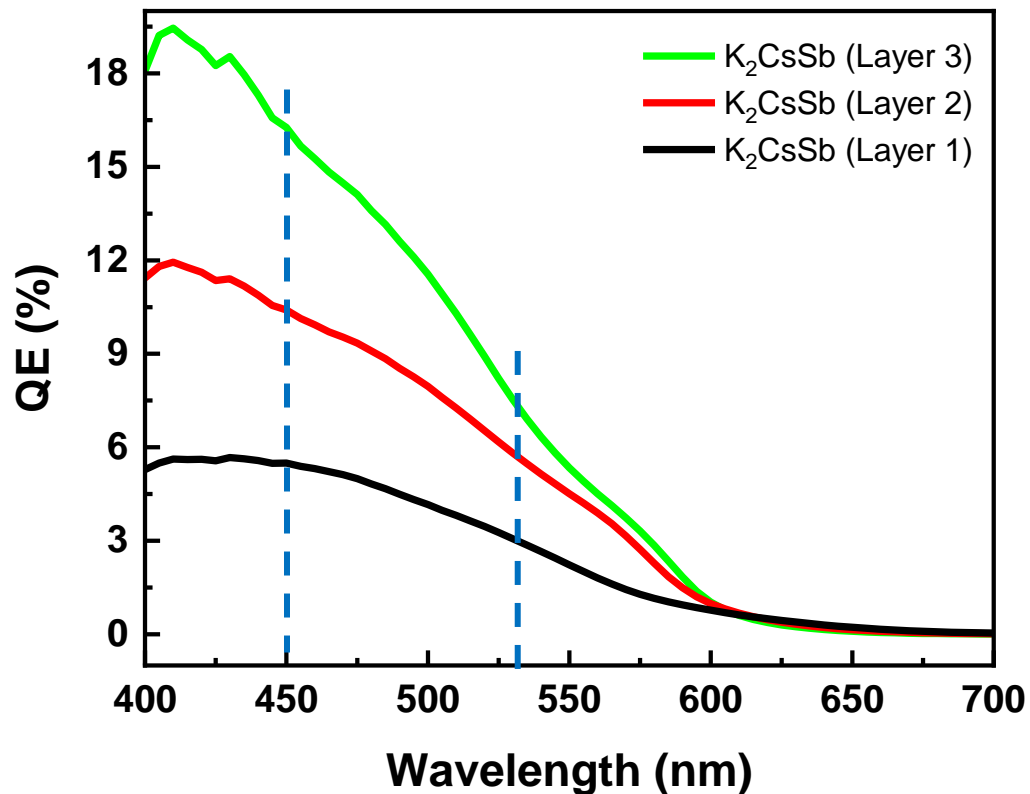
K_2CsSb (Layer 3)

K_2CsSb (Layer 2)

K_2CsSb (Layer 1)

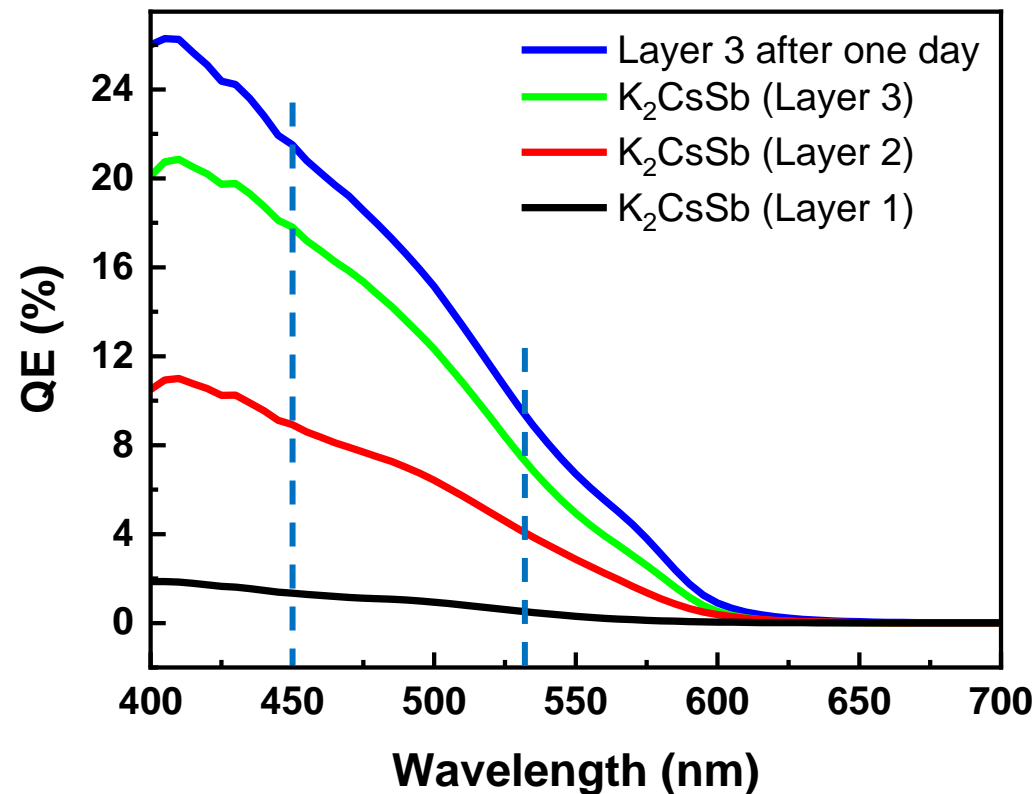
Substrate

Spectral response from Sample 2



Wavelength (nm)	Sample-2 QE (%)		
	L1	L2	L3
450 (Blue)	5.5	10.4	16.3
530 (Green)	3.1	5.8	7.5

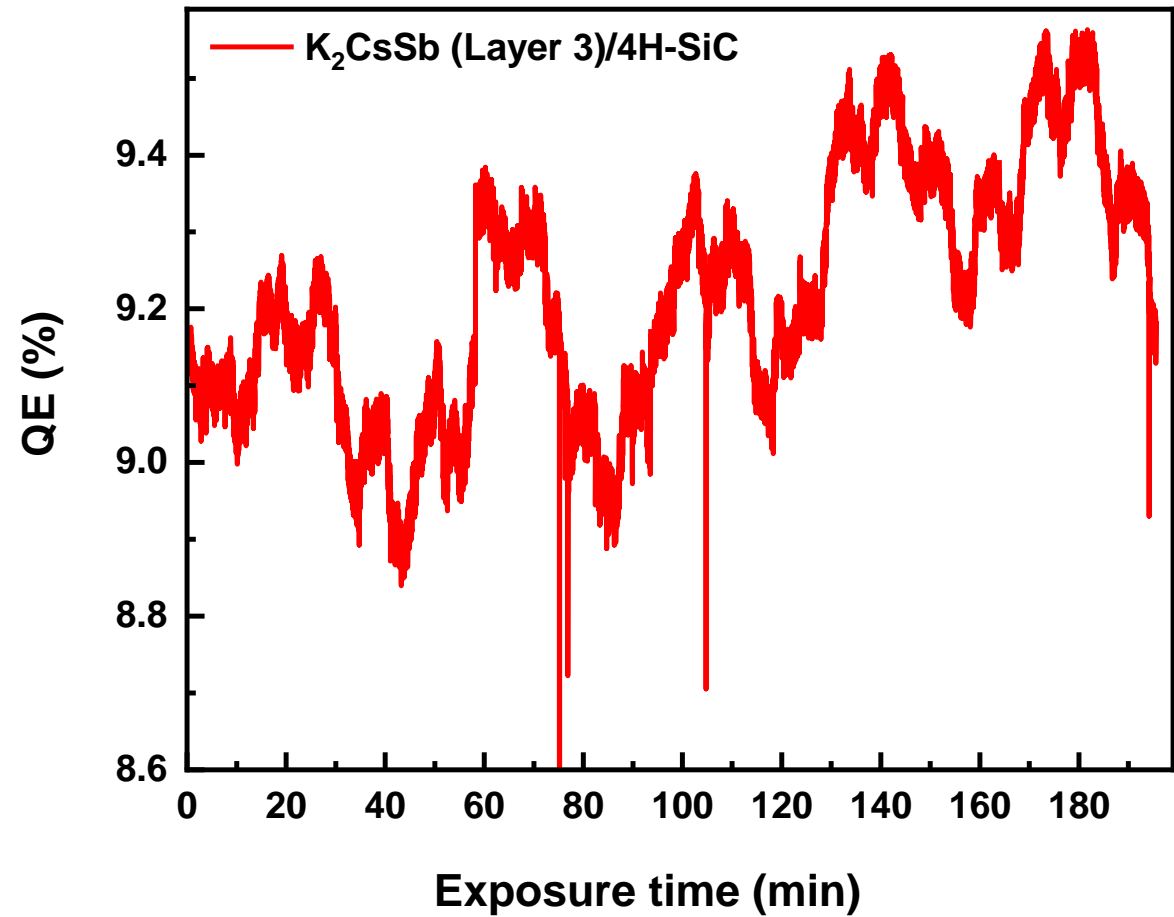
Spectral response from Sample 3



Wavelength (nm)	Sample-3 QE (%)			
	L1	L2	L3	L3 after 1 day
Green laser	0.5	4.6	9.2	--
LDLS source	450	1.3	8.9	17.8
	530	0.5	4.2	7.6

Lifetime of $K_2CsSb/4H-SiC$ using Green laser

- ☐ Measured QE after 3-4 days
- ☐ Current draw about 25 μA
- ☐ No decay in QE
- ☐ Fluctuations from laser power



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- **Conclusions**
- Acknowledgement

Conclusion

- ❑ Successful in growing epitaxial thin film of photocathode.
- ❑ RHEED provides
 - Epitaxial growth of photocathode
 - Photocathode films formed are smooth surface
 - Azimuthal angular dependence observed
 - PLD and thermal grow similar structure
- ❑ XRR provides
 - Photocathode film thickness, roughness, electron density
 - Film roughness < 0.8 nm
- ❑ QE measurements provide QE of photocathode thin film
 - QE got for green laser > 9%.
- ❑ XRD provides crystalline structure not only from the surface but also from bulk
 - Azimuthal angular dependence observed

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- Acknowledgement

Acknowledgements

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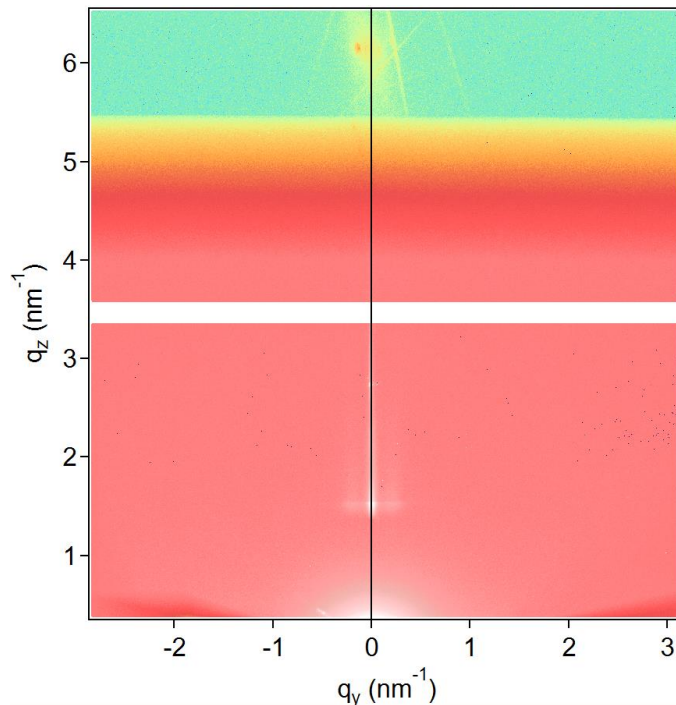
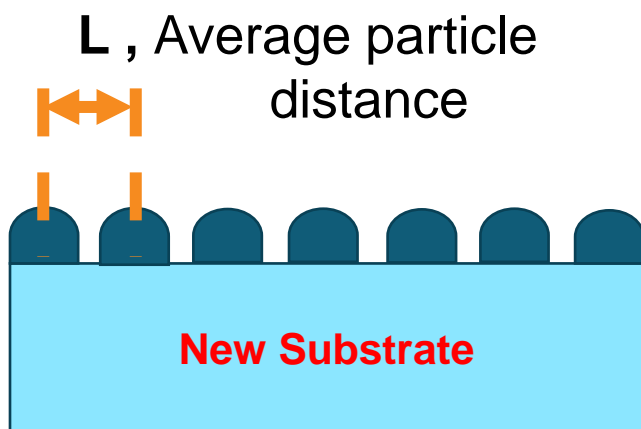
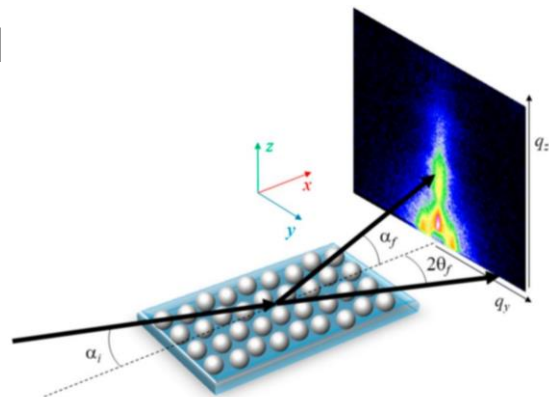
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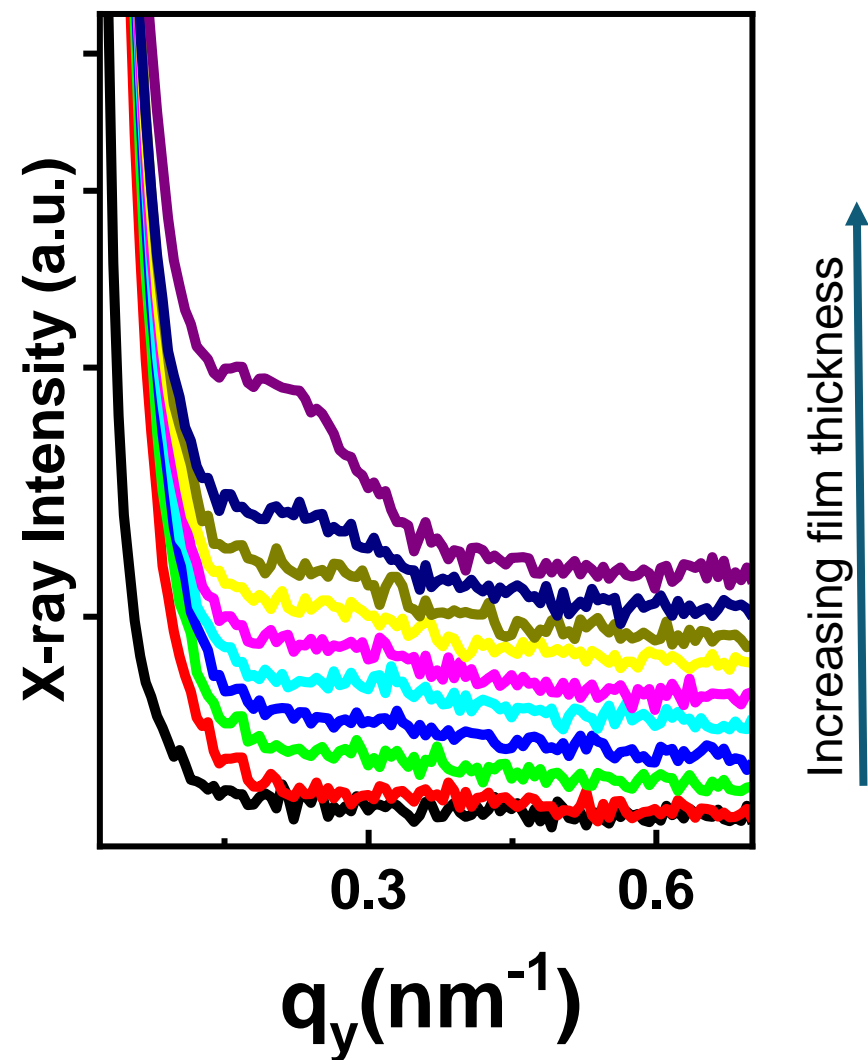
Thank You

GISAXS: Photocathode on single crystal

- ❑ Morphology and distribution of either islands on a substrate or buried particles.
- ❑ Structural details of thin film like correlations, Shape, Size of density inhomogeneities at surfaces or at buried interfaces.
- ❑ Depth sensitivity from surface to buried interfaces up to a few hundreds of nanometers can be probed by varying the angle of incidence.



GISAXS Image



GISAXS of K_2CsSb

- ❑ Layer 1: average particle distance 35 nm.

